10/522,059 MAT-8640US

Application No.: Amendment Dated:

April 14, 2010

Reply to Office Action of: January 14, 2010

Amendments to the Claims:

This listing of claims will replace all prior versions, and listings, of claims in the application.

Listing of Claims:

1. (Currently Amended) A method of manufacturing a plasma display panel, the method comprising the steps of:

providing a substrate holder above a source of deposition material, the substrate holder including:

a <u>plurality of first frames</u> for holding a <u>plurality of substrates for a respective plurality</u> of the <u>plasma plasma display panels</u>, said <u>plurality of first frames holding the substrate has have a protrusion extending between them which extends from below a bottom surface of the substrate along a side surface of the substrate to a height above the substrate and greater than a height of the substrate without being superimposed over the top surface of the substrate; and</u>

a <u>plurality of second frames each</u> having <u>a respective opening</u>, <u>an</u> opening, the protrusion between the substrate and the opening so that the substrate is on one side of the protrusion and the opening is on the other side of the protrusion protrusions situated between each of the second frames and the plurality of first frames so that the substrates are on one side of each of the protrusions and each respective opening is on another side of each of the protrusions, the protrusions also extending above the substrates without being superimposed over the tops of the substrates, and an unobstructed path exists from said source of deposition material to a top surface of said substrate;

providing the plasma display panel which is held by the substrate holder for deposition;

spraying said deposition material onto said bottom surface of said substrate from below the substrate;

Application No.: Amendment Dated: 10/522,059 April 14, 2010

Reply to Office Action of: January 14, 2010

and permitting an additional amount of said deposition material to flow through said opening from below the substrate.

- (Previously Presented) The method of manufacturing a plasma display 2. panel as defined in Claim 1, wherein a height of the protrusion is between 1 mm and 100 mm.
- (Previously Presented) The method of manufacturing a plasma display 3. panel as defined in Claim 1, the first frame comprising holding means including support means for supporting the substrate from underneath and positioning means for positioning the substrate in a planar direction, wherein the substrate is held by fitting the substrate to the positioning means and placing the substrate on the support means.
- (Currently Amended) A substrate holder system for a plasma display 4. panel, the substrate holder system comprising:
- a plurality of first frames for holding a <u>plurality of substrates for a respective</u> plurality of the plasma plasma display panels, said plurality of first frames being provided with a protrusion extending between them which extends from below a bottom surface of the substrate along a side surface of the substrate to a height above the substrate greater than a height of the substrate without being superimposed over the top surface of the substrate,

a <u>plurality of second frames each</u> having <u>a respective opening</u>, an opening, the protrusion between the substrate and the opening so that the substrate is on one side of the protrusion and the opening is on the other side of the protrusionprotrusions situated between each of the second frames and the plurality of first frames so that the substrates are on one side of each of the protrusions and each respective opening is on another side of each of the protrusions, the protrusions also extending above the substrates without being superimposed over the tops of the substrates;

and a source of deposition material below said substrate which sprays said deposition material towards the bottom surface of the substrate and through the opening;

Application No.: 10/522,059
Amendment Dated: April 14, 2010
Reply to Office Action of: January 14, 2010

wherein an unobstructed path exists from said source of deposition material to a top surface of said substrate.

- 5. (Previously Presented) The substrate holder system for a plasma display panel as defined in Claim 4, wherein a height of the protrusion is between 1 mm and 100 mm.
- 6. (Previously Presented) The substrate holder system for a plasma display panel as defined in Claim 4, the first frame comprising holding means including support means for supporting the substrate from underneath and positioning means for positioning the substrate in a planar direction, wherein the substrate is held by fitting the substrate to the positioning means and placing the substrate on the support means.
- 7. (Previously Presented) The substrate holder system for a plasma display panel as defined in Claim 4, wherein the first frame includes a plurality of supports separated from each other which extend below the bottom surface of the substrate.
- 8. (Previously Presented) The substrate holder system for a plasma display panel as defined in Claim 4, said second frame maintained with said opening while said substrate is situated in said first frame.
- 9. (Previously Presented) A method of manufacturing a plasma display panel as defined in Claim 1, wherein the protrusion curves away from the substrate.